

Si

EE105

Microelectronic Devices and Circuits:

MOS Capacitor

Metal oxide semiconductor

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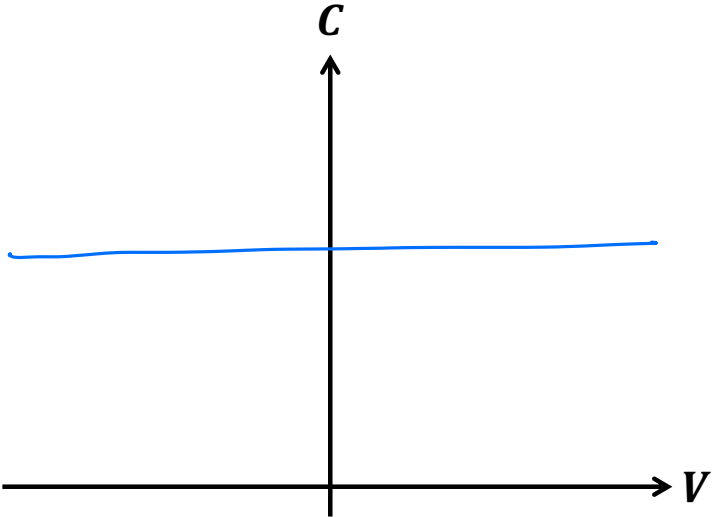
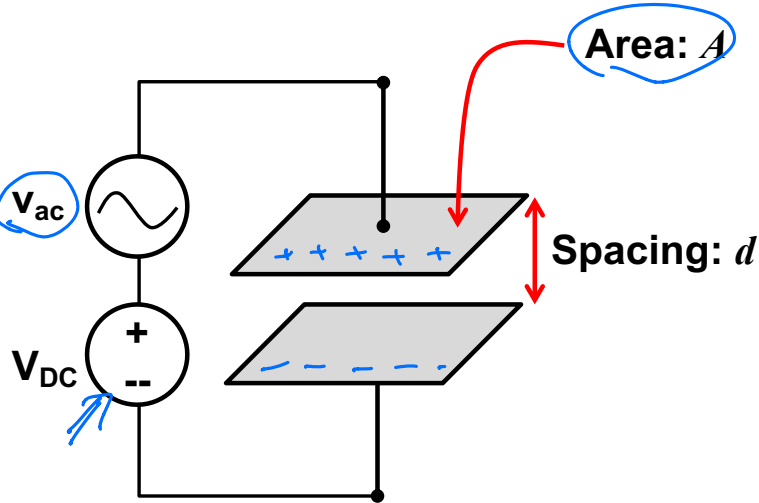
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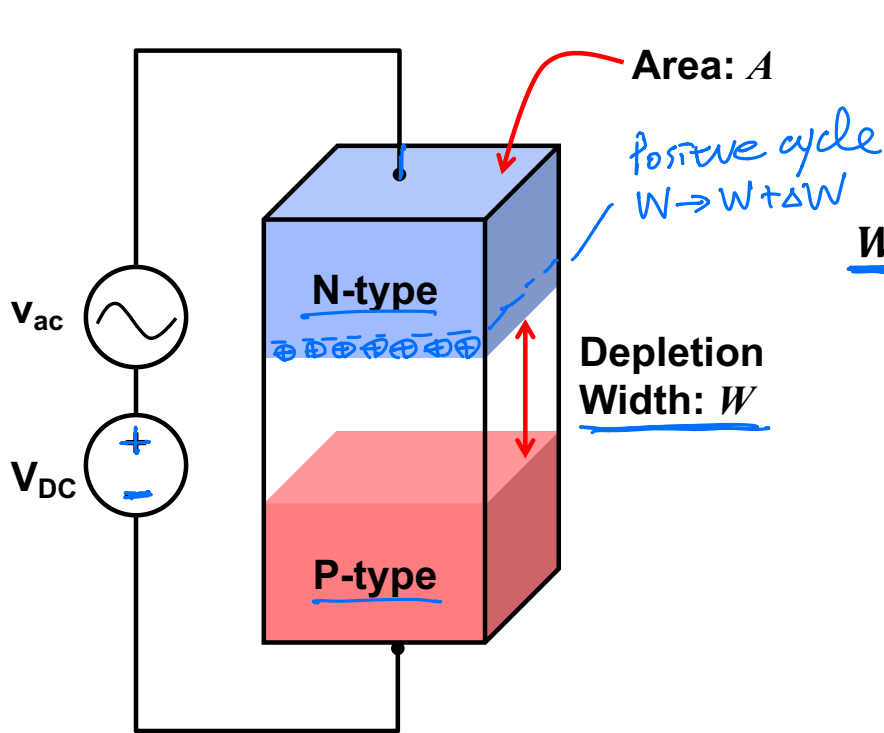
Linear Capacitor

$$C = \frac{\epsilon A}{d}$$

Area (handwritten label pointing to A)
spacing (handwritten label pointing to d)



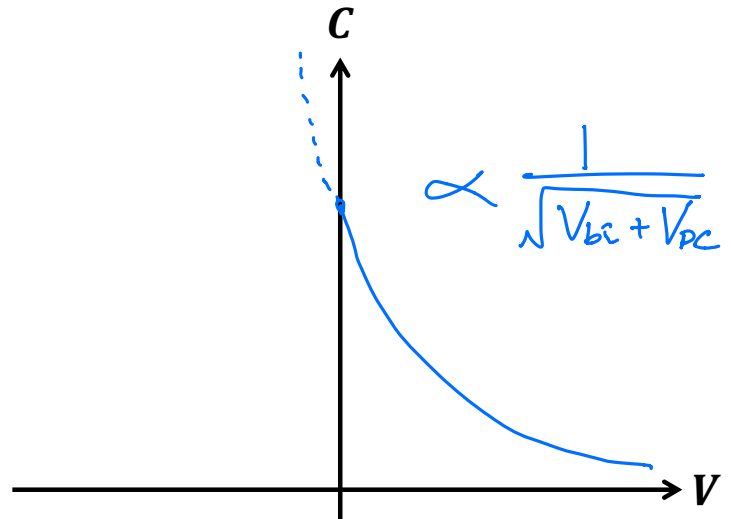
Nonlinear Capacitor – Reverse-Biased PN Junction



Behave exactly like parallel plate cap

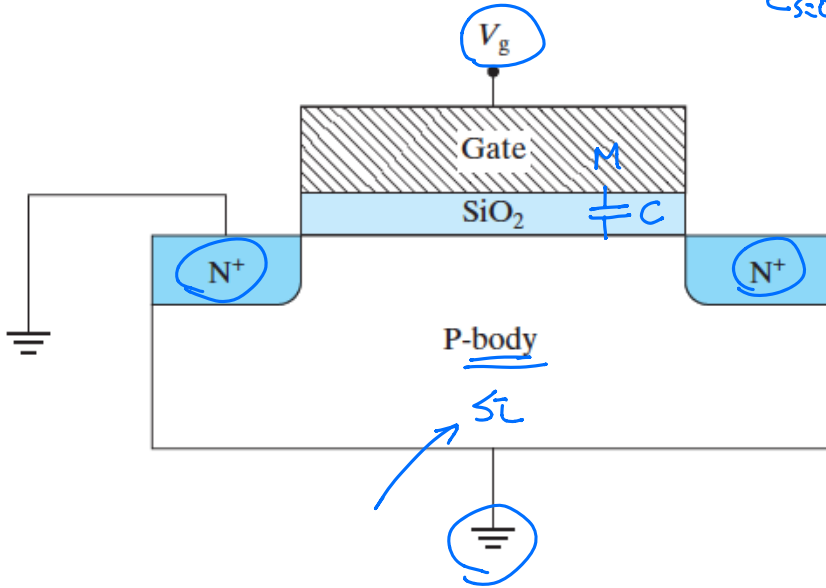
$$C = \frac{\epsilon A}{W}$$

$$W = \sqrt{\frac{2\epsilon_s}{q} \left(\frac{1}{N_D} + \frac{1}{N_A} \right) (V_{bi} + V_{DC})}$$



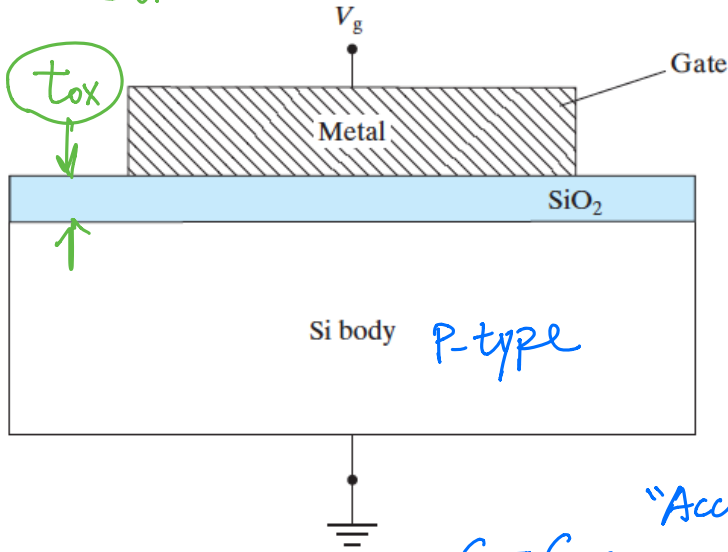
Metal-Oxide-Semiconductor (MOS): Integral Part of MOS Transistor

$$\epsilon_{\text{SiO}_2} = 3.9 \cdot \epsilon_0$$

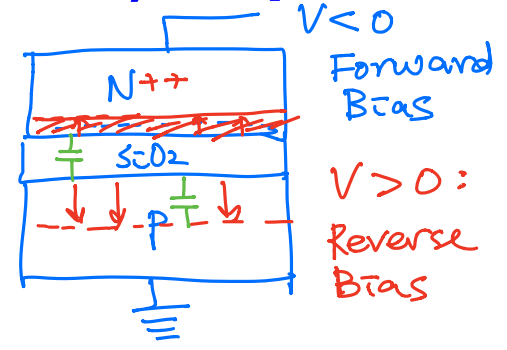


Metal-Oxide-Semiconductor (MOS) Capacitor

$\epsilon_{Si} \sim 12 \cdot \epsilon_0$
 $\epsilon_{Ox} \sim 4 \epsilon_0$



Think
 Depletion
 Region



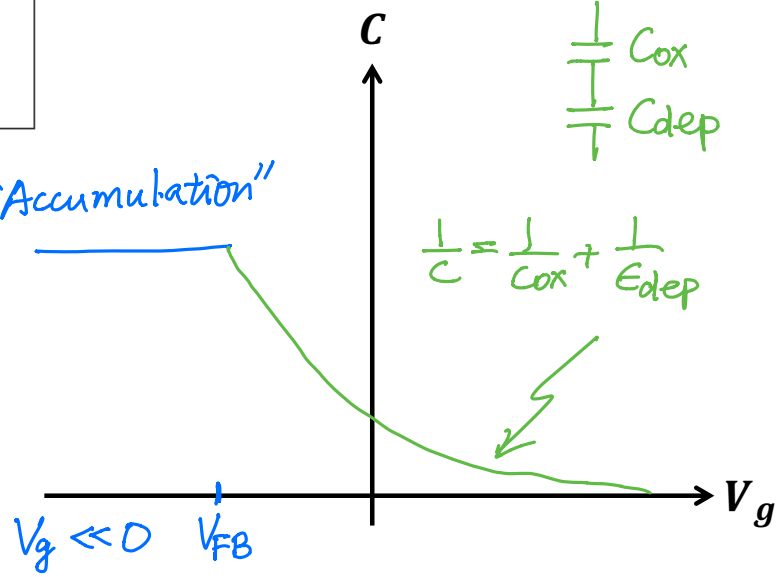
V_{FB} = Flat Band

C_{dep} = depletion cap. = $\frac{\epsilon_{Si}}{W}$

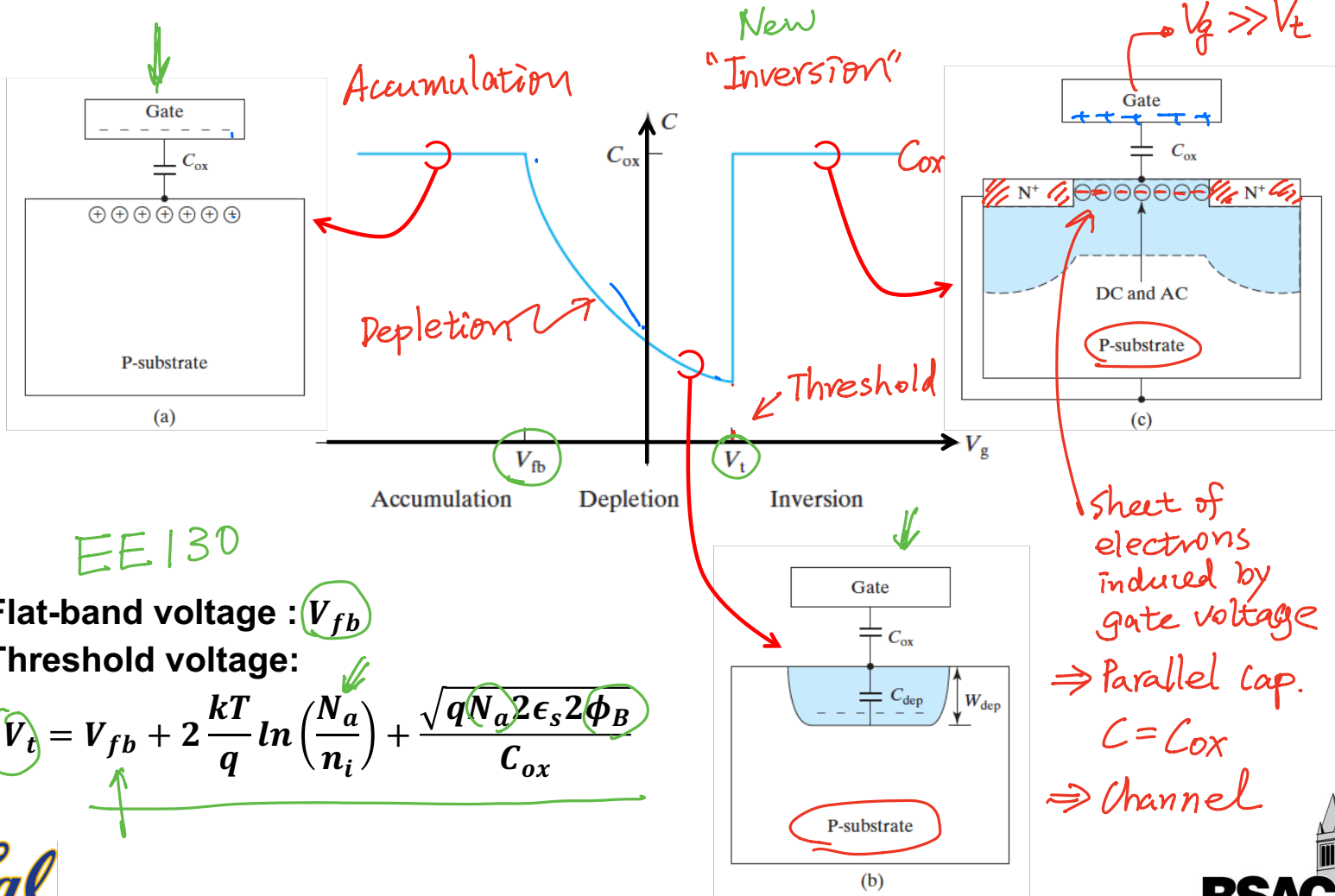
C_{ox} = oxide cap = $\frac{\epsilon_{SiO_2}}{t_{ox}} = \frac{\epsilon_{ox}}{t_{ox}}$
 t_{ox} : thickness of oxide

$C = C_{ox}$

"Accumulation"



C-V Curve of MOS Capacitor



EE130

Flat-band voltage: V_{fb}

Threshold voltage:

$$V_t = V_{fb} + 2 \frac{kT}{q} \ln \left(\frac{N_a}{n_i} \right) + \frac{\sqrt{q N_a 2 \epsilon_s 2 \phi_B}}{C_{ox}}$$

Sheet of electrons induced by gate voltage
 \Rightarrow Parallel cap.
 $C = C_{ox}$
 \Rightarrow Channel